

a microwave transparent, gas tight barrier through which said source of microwave radiation is directed into said reaction chamber;

a microwave reflecting enclosure into which said source of microwave radiation is directed;

a manifold for gas delivery adapted to receive the generated gas; and

a solvent vapor removal device adapted to remove solvent vapor from the generated gas.

33. (New) The system of claim 32, also comprising a supply of precursor material coupled to said reaction chamber.

34. (New) The system of claim 33, also comprising:

a gas concentration sensor for sensing gas concentration in the generated gas; and

a feed-back control system to control gas generation rate in said reaction chamber.--

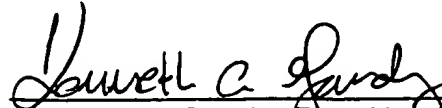
### **REMARKS**

In response to the restriction requirement set forth in the Office Action, Group II, claims 1-21, is hereby elected. In addition, the Examiner will note that claims 32-34 have been added in the above amendment. These claims are similarly directed to chemical reactor systems, and it is therefore believed that they should be properly grouped with Group II. Examination of claims 1-11 and 32-34 is therefore solicited.

The Examiner is encouraged to contact the undersigned attorney by telephone if there are any questions about this submission.

Respectfully submitted

By:



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